Field Enhancement Determination of Near-field Probes Through Photoemission Electron Microscopy

> Conor Zellmer Dr. Erik Sánchez Nano-Development Lab Portland State University REU Program 18 August 2014

Agenda

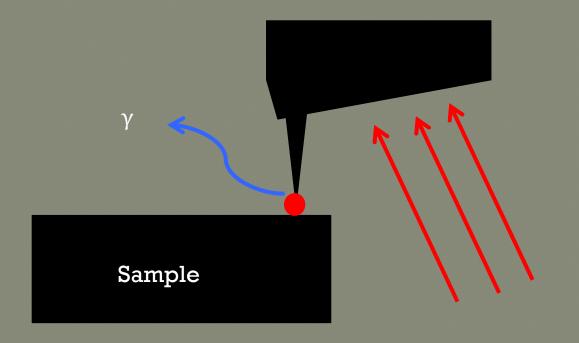
Theory Overview
Project Overview
Detector Issue and Re-design
Milling Project

TENOM

Tip Enhanced Near-field Optical Microscopy

- Diffraction Limit
- Optical microscope with nano-scale resolution
- Photoemission Electron Microscope (PEEM)

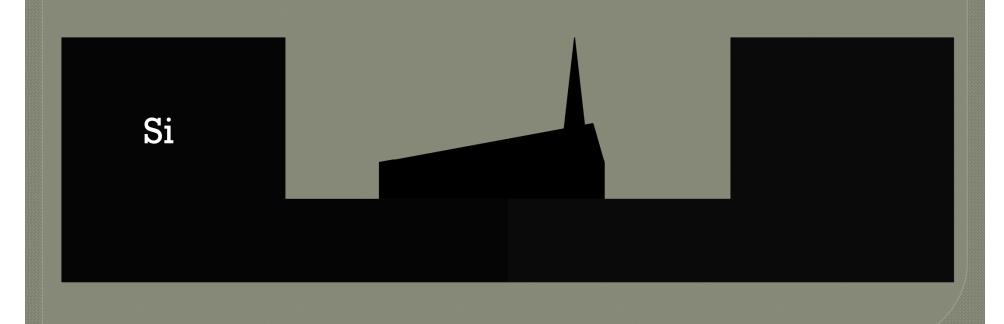
Theory Overview



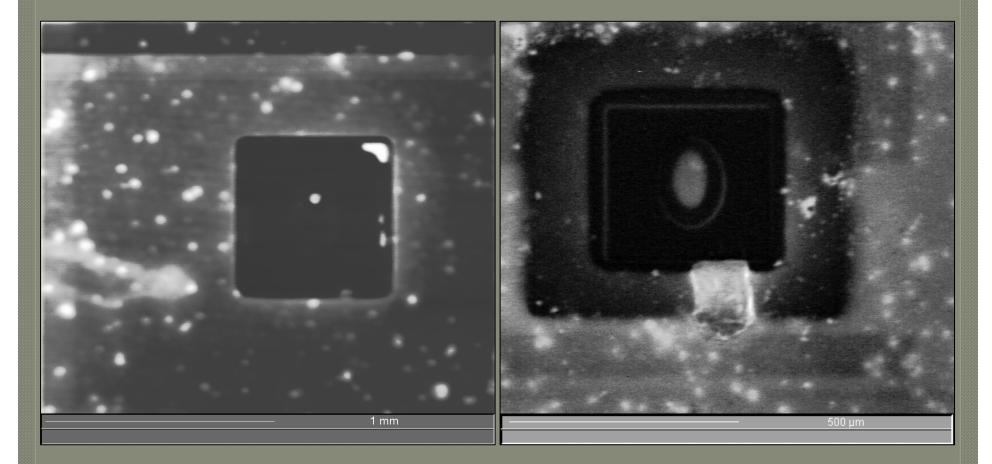
Project Overview

Fabricate near-field probe tips Focused Ion Beam (FIB) Grayscale bitmap template 'Bird's eye view'

Project Overview

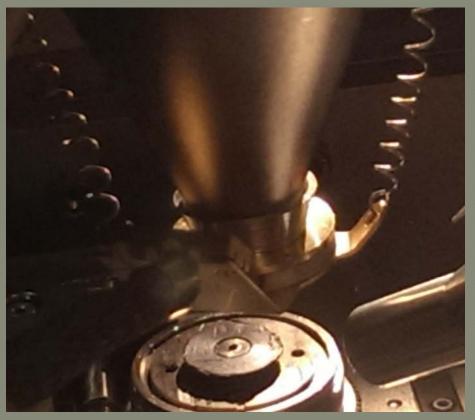


Detector Issue



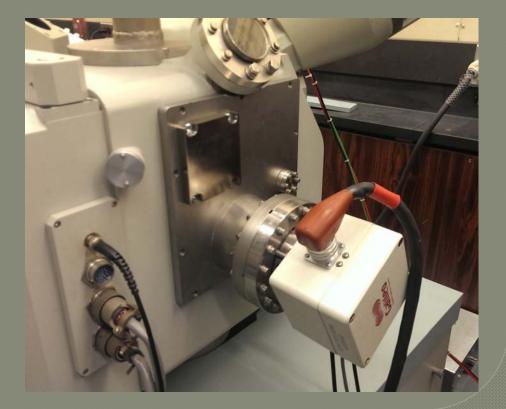
Design

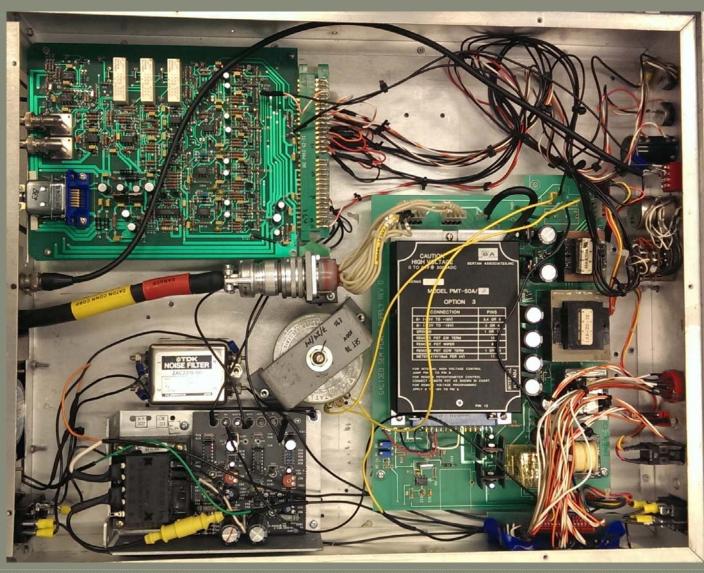
- SEM Micro Channel Plate Detector
 - JEOL Galileo Detector
- Reconfigured for FEI 611 FIB



Construction

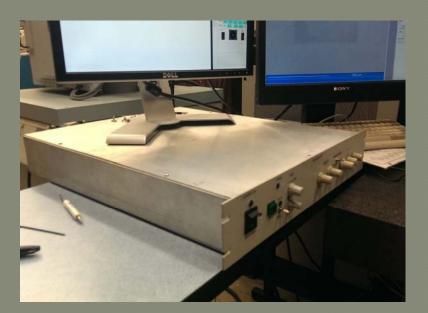
- Rewired and machined
 - 19" rack mount
 - Control board
 - Power Supply
 - Switches and knobs





Implementation

- Software
 - Look Up Table error





Milling

Optimizing Pattern

- Lens 1 Voltage (Beam Current)
- Max Dwell
- Pattern Time
- Magnification

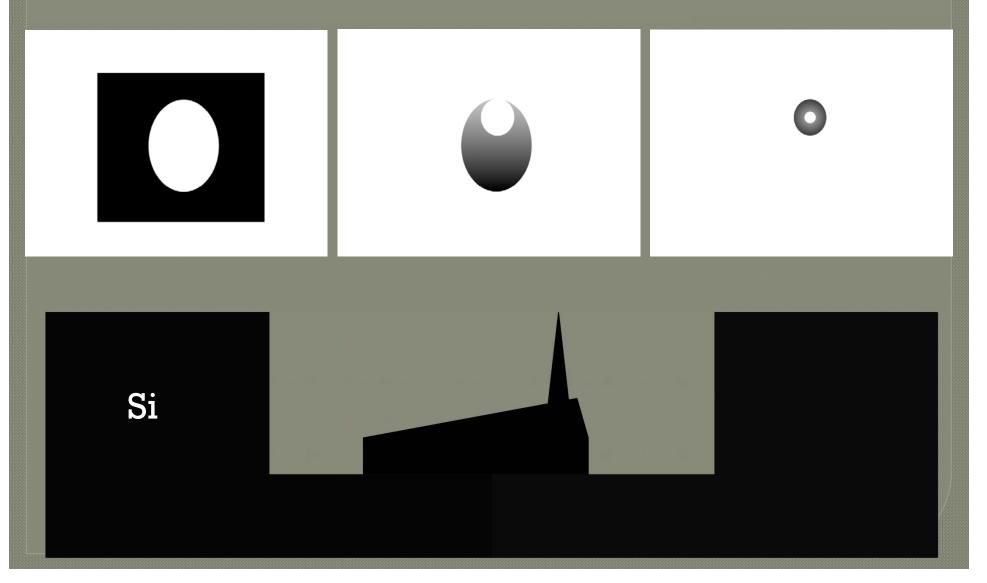


"Patterns 1.04"

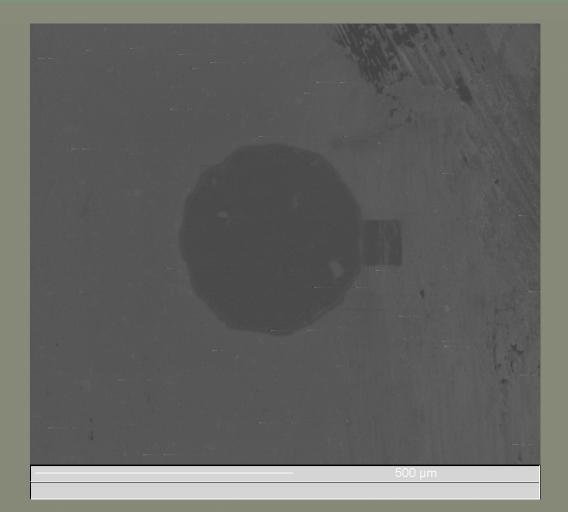
1995 FEI Visual Basic 4 program Converts bitmaps to FEI Stream files

Patterns 1.04	- 🗆	×
File		
Pattern Type O Circle Rectangle MS Windows .BMP Vertical Grating Lens		
Dwell Profile © Constant © Lin. Increase © Lin. Decrease Field of View: 28.85um Magnification	Max Dwell, uS120Min Dwell, uS0Dwell, uS10Pattern Time, mins8Overlap, %-300Spotsize, um0.5	
Number of Dwell Pts: 113830	BMP Size 28.85 BMP XFac 1.03	

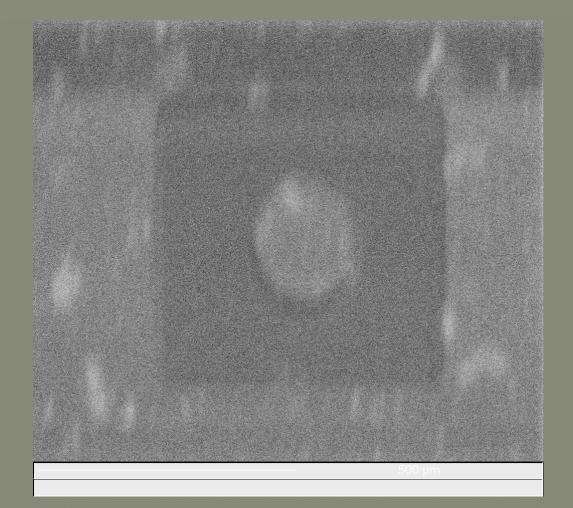
Milling Patterns



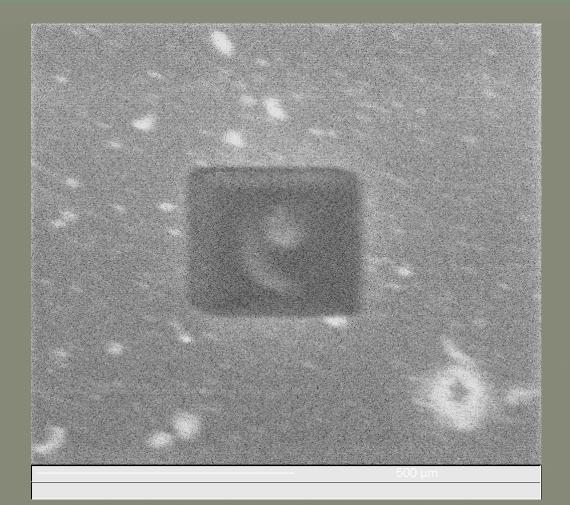
Milling Results



Milling Results



Milling Results



Conclusions

Another new detector

- Different MCP designed for a FIB
- New Charge Detection Electron Multiplier (CDEM)

Work will be continued until the project is complete

Acknowledgments

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NSF



References

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Richards, David. "Near-Field Microscopy: Throwing Light on the Nanoworld." Mathematics, Physics and Engineering 361.1813 (2003): 2843-857. JSTOR. The Royal Society, 15 Dec. 2003. Web. 06 Aug. 2014.

Sánchez, E., A. Dunham, D. Nowak, J. Straton, and J. Doughty. "Enhanced Image Contrast with Delocalized Near-Field Excitation." *Crystal Research and Technology* DOI 10.1002/crat.201300325 (2014): n. pag. Wiley Online Library, 9 Jan. 2014. Web. 13 Aug. 2014.